

TRANSMITTAL

Electronic Version v1.1

Stylesheet Version v1.1.0

Title of Invention	Method of Forming Thin Silicon Oxide Films on Silicon Carbide Substrates	
Application Number :		
Date :		
First Named Applicant:	Andrew M. Hoff	
Confirmation Number:		
Attorney Docket Number:	1372.80.PRC	
<p>I hereby certify that the use of this system is for OFFICIAL correspondence between patent applicants or their representatives and the USPTO. Fraudulent or other use besides the filing of official correspondence by authorized parties is strictly prohibited, and subject to a fine and/or imprisonment under applicable law.</p> <p>I , the undersigned, certify that I have viewed a display of document(s) being electronically submitted to the United States Patent and Trademark Office, using either the USPTO provided style sheet or software, and that this is the document(s) I intend for initiation or further prosecution of a patent application noted in the submission. This document(s) will become part of the official electronic record at the USPTO.</p>		
Submitted By:		Elec. Sign.
Anton J. Hopen Registered Number: 41849		/anton j hopen/ Attorney

Documents being submitted:	Files
us-request	1372_80_PRC-usrequ.xml us-request.dtd us-request.xsl
us-declaration	1372_80_PRC-usdecl.xml us-declaration.dtd us-declaration.xsl
us-fee-sheet	1372_80_PRC-usfees.xml us-fee-sheet.xsl us-fee-sheet.dtd
us-power-of-attorney-grant	1372_80_PRC-uspoat.xml us-power-of-attorney-grant.dtd us-power-of-attorney-grant.xsl
application-body	Specification-trans.xml us-application-body.xsl application-body.dtd wipo.ent mathml2.dtd mathml2-qname-1.mod isoamsa.ent isoamsb.ent isoamsc.ent isoamsn.ent isoamso.ent isoamsr.ent isogr3.ent isomfrk.ent isomopf.ent isomscr.ent isotech.ent isobox.ent isocyr1.ent isocyr2.ent isodia.ent isolat1.ent isolat2.ent isonum.ent isopub.ent mmlextra.ent mmlalias.ent soextblx.dtd FIG0102_1.TIF
Comments	